

Monolithic Two-Tier Dual Gated Ga-doped In₂O₃ 1T-1C Memory Cell for Bit Cost Scalable 3D FeRAM

Eknath Sarkar, Jay Sonawane, Emmanuel Quezada, S. E. Wodzro, P. K. Hsu, D. Chakraborty, O. S. Phadke, F. G. Wakar, C. Zhang, J. Shin, H. Park, H. J. Lee, M. Tian, A. I. Khan, Shimeng Yu, and Suman Datta

School of Electrical and Computer Engineering, Georgia Institute of Technology, Atlanta, Georgia 30332, USA

Email: esarkar6@gatech.edu

Ferroelectric Hafnium-Zirconium-Oxide (HZO) memories have recently emerged as promising refresh-free RAM solutions [1]. Among them, the one-transistor-one-capacitor (1T1C) FeRAM offers robust endurance, retention, low-voltage operation, and scalability. To address growing AI-driven memory demands, BEOL-compatible monolithic 3D stacking enables higher densities with minimal footprint. Bit-cost scalable designs are key for practical 3D integration. Amorphous oxide semiconductor (AOS) MOSFETs, such as indium tungsten oxide (IWO) [2] or indium gallium oxide (IGO), offer BEOL compatibility, ultra-low off-current, high mobility, strong electrostatic control, and suitability for advanced architectures, making them strong candidates for 3D 1T1C FeRAM access devices.

We present a compact 3D integration of vertically stacked 1T1C ferroelectric memory (FeRAM) cells, as illustrated in Fig. 1(a–b), featuring common gate architecture and vertical bit-line (VBL) connectivity for enhanced scalability. The cross-sectional STEM images (Fig. 1(c–d)) and EDS mapping (Fig. 1(e)) confirm successful stacking of dual-gate (DG) MOSFETs and ferroelectric capacitors (FeCAPs), utilizing 5 nm HZO and ~800 nm gate lengths. The DG MOSFETs employ gallium-doped indium oxide (IGO) channels with 18% Ga doping, fabricated via an ALD super-cycle process (1 Ga cycle per 4 In₂O₃ cycles). Electrical characterization of FeCAPs in Tier 1 and Tier 2 reveals minor loop P-V behavior (Fig. 1(f)), pulse-width-dependent switching dynamics (Fig. 1(g)), and endurance under 100%, 50%, and 75% switching conditions (Fig. 1(h)). Transfer characteristics (Fig. 1(i)) demonstrate independent threshold voltage (V_T) modulation via control gates, while output curves (Fig. 1(j)) show clear current saturation and high I_{on} , confirming the suitability of this architecture for high-performance 3D FeRAM applications. Fig. 2 illustrates the functional and simulated performance of the proposed 3D-stacked 1T1C FeRAM architecture. The write scheme (Fig. 2(a)) applies tier-specific voltages (0.8 V, 1.4 V, 2.0 V) to the bit-line (BL) with grounded plate-line (PL) for writing ‘1’, and reverses polarity for writing ‘0’, with monotonic BL current confirming successful programming. Destructive read operations (Fig. 2(b)) ramp PL from 0.4 V to 2.0 V in 0.2 V steps following a -2 V pre-erase, validating read accuracy across tiers. Polarization versus read voltage data (Fig. 2(c)) shows strong ferroelectric response ($>40 \mu\text{C}/\text{cm}^2$ above 1.2 V), while retention measurements (Fig. 2(d)) demonstrate stability up to 10^4 s at 25°C, with projections extending to 10 years. TCAD mixed-mode simulations (Fig. 2(e–j)) model the stacked DG IGO MOSFETs and MFM capacitors, with calibrated results (Fig. 2(f)) matching experimental data. Scaled projections (Fig. 2(g)) indicate high I_{on} (186 μA) and low I_{off} , and simulated sensing waveforms (Fig. 2(h–j)) confirm reliable readout of both ‘Data 1’ and ‘Data 0’, supporting the architecture’s feasibility for robust 3D FeRAM operation.

References

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* Corresponding author: email: esarkar6@gatech.edu

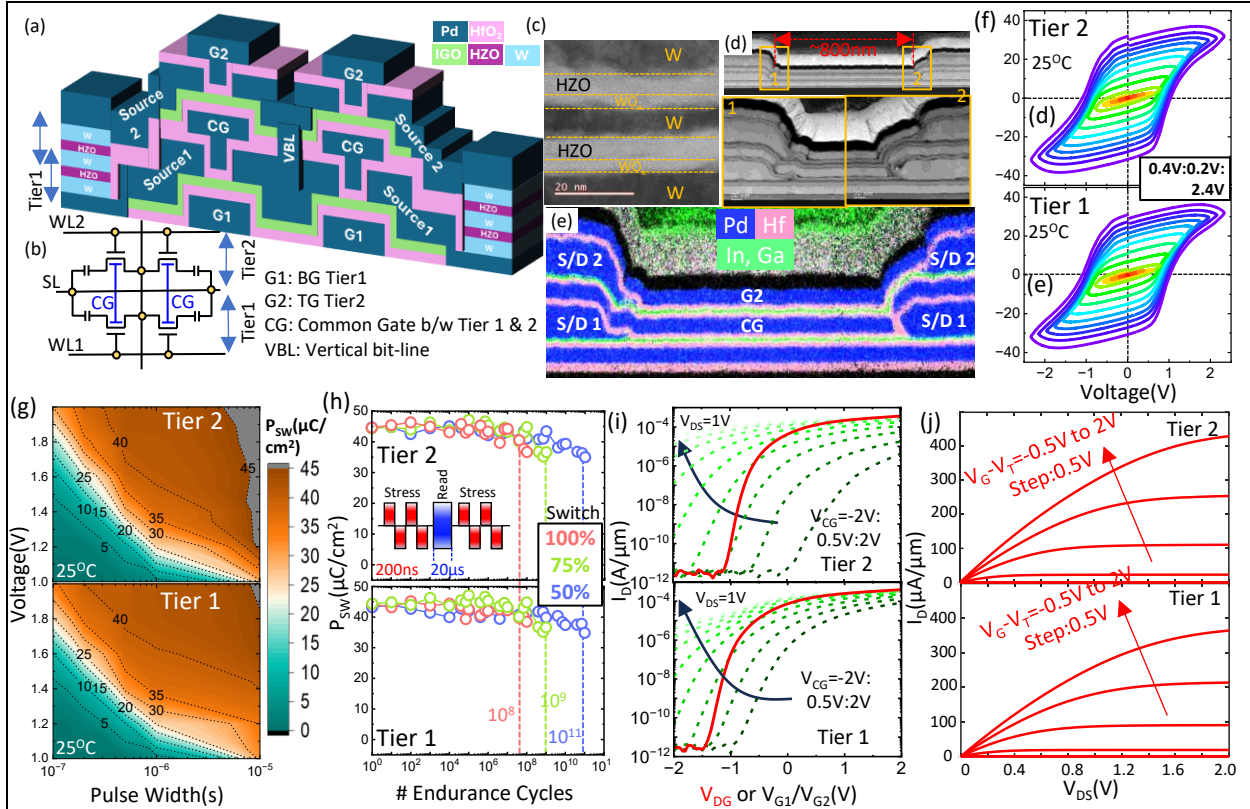


Fig. 1 (a) 3D schematic illustrating the vertically stacked 1T1C cells, VBL connections; (b) Circuit schematic showing the 2-layer stacked 1T1C FeRAM structure with common gates and vertical bit-lines for compact integration; (c) Cross-sectional STEM of 2-stacked FE CAPs with 5 nm HZO; (d) STEM of 2-stacked DG IGO MOSFET showing ~800 nm gate length; (e) EDS mapping confirms element locations and successful stacking of 2 DG MOSFETs; (f) Minor loop P-V characteristics of ferroelectric capacitors (FeCAPs) in Tier 1 and Tier 2; (g) Pulse-width-dependent switching behavior of FeCAPs in both tiers. (h) Endurance characteristics of 2-stacked FeCAPs under 100%, 50%, and 75% switching conditions; Vertically stacked DG MOSFETs using gallium-doped indium oxide (IGO) channels with 18% Ga doping, fabricated via ALD super-cycle process (1 Ga cycle per 4 In_2O_3 cycles); (i) Transfer characteristics of Tier 1 and Tier 2 MOSFETs, where independent control of the CG enables V_T modulation. Devices with DG operation exhibit enhanced performance with tunable V_T ; (j) Output characteristics of the DG MOSFETs showing clear current saturation and high I_{ON} , demonstrating suitability for 3D FeRAM applications.

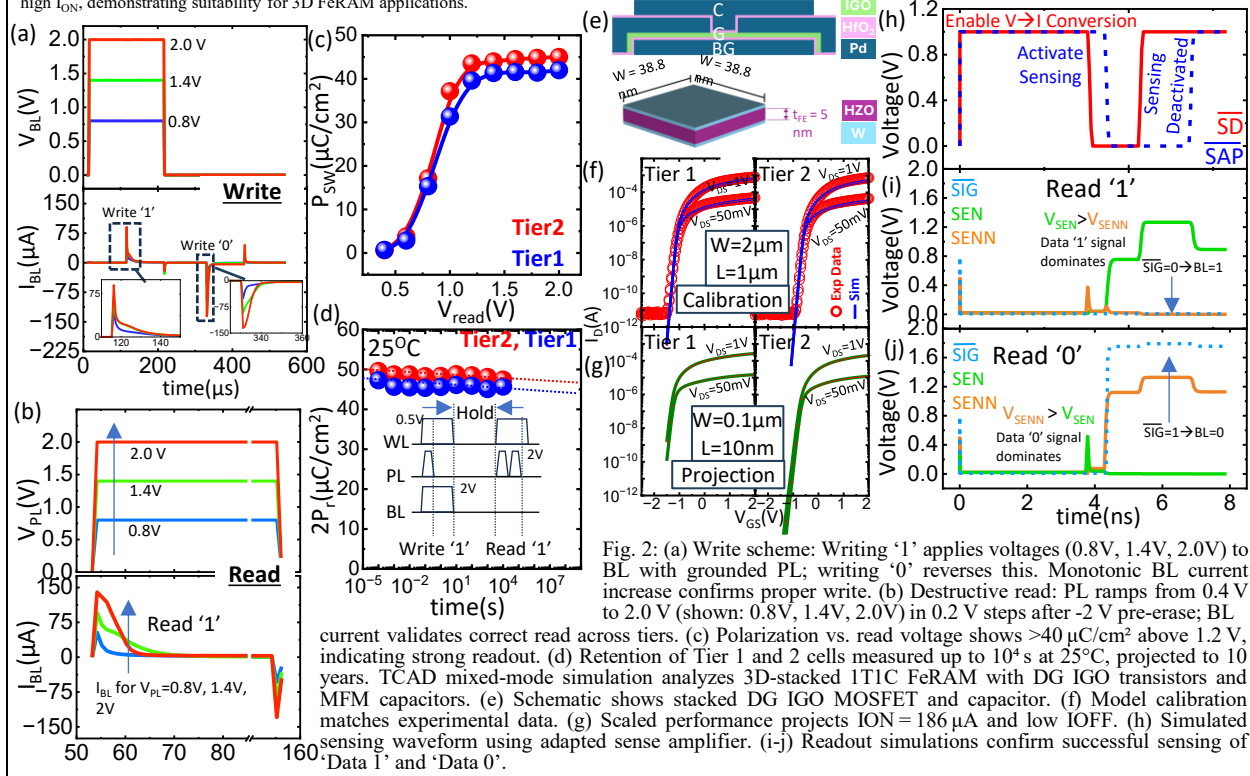


Fig. 2: (a) Write scheme: Writing '1' applies voltages (0.8V, 1.4V, 2.0V) to BL with grounded PL; writing '0' reverses this. Monotonic BL current increase confirms proper write. (b) Destructive read: PL ramps from 0.4 V to 2.0 V (shown: 0.8V, 1.4V, 2.0V) in 0.2 V steps after -2 V pre-erase; BL current validates correct read across tiers. (c) Polarization vs. read voltage shows $>40 \mu\text{C}/\text{cm}^2$ above 1.2 V, indicating strong readout. (d) Retention of Tier 1 and 2 cells measured up to 10^4 s at 25°C , projected to 10 years. TCAD mixed-mode simulation analyzes 3D-stacked 1T1C FeRAM with DG IGO transistors and MFM capacitors. (e) Schematic shows stacked DG IGO MOSFET and capacitor. (f) Model calibration matches experimental data. (g) Scaled performance projects $I_{\text{ON}} = 186 \mu\text{A}$ and low IOFF. (h) Simulated sensing waveform using adapted sense amplifier. (i-j) Readout simulations confirm successful sensing of Data '1' and 'Data 0'.